

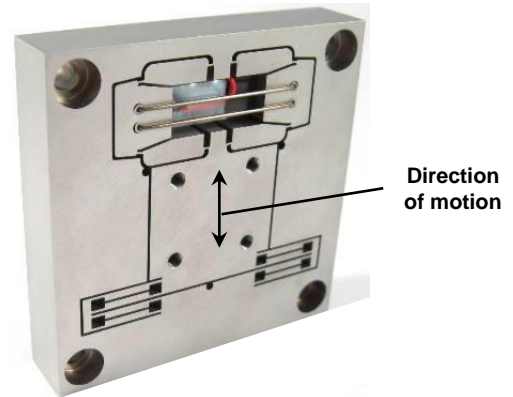
XSA-0200C: 200 micron Nanopositioning Stage

Description

DSM's nanopositioning piezoelectric XSA-0200C stage features flexure-guided motion over a 200 micron travel range for scanning, metrology, inspection processes, and other precision applications. The stage's stable and stiff kinematic design promotes parallelism in the output motion with minimal pitch and yaw as well as dynamic responsiveness for excellent position, stability, and control.

Specifications

- Nominal Travel, 0V to 150V: 170 $\mu\text{m} \pm 10\%$
- Nominal Travel, -30V to 150V: 200 $\mu\text{m} \pm 10\%$
- Stiffness: 0.8 N/ $\mu\text{m} \pm 10\%$
- Linearity: 0.12% typical
- Pitch / Yaw: <20 μrad typical
- Unloaded Resonant Freq: 420 Hz $\pm 10\%$
- Blocking Force: 136 N $\pm 10\%$
- Push/Pull Force Capacity: 40 N Max
- Load Capacity: 50 N Max
- Lateral Load Capacity: 20 N Max
- Electrical Capacitance: 3.6 $\mu\text{F} \pm 10\%$
- Operating Temp Range: -20 to 80 °C
- Operating Voltage: -30 to 150 V
- Motion Direction: Contracting (towards piezo stack)
- Dimensions: 60 x 60 x 12.5 mm
- Mass: 0.31 kg $\pm 10\%$
- Material: Stainless steel
- Cable Length: 1 m (custom lengths available)



Application Fields

- Precision Manufacturing
- Microscopy
- Laser systems
- Material Science
- Optics/Photonics
- Electronics Manufacturing
- Science & Research institutions
- Test & Inspection Systems

